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Osmalls-Logan
PATENT
2-12-03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Satya et al.

Attorney Docket No.: KLA1P016F/P642

Application No.: 09/648,095

Examiner: P. Cao

Filed: August 25, 2000

Group: 2811

Title: CHEMICAL MECHANICAL POLISHING
TEST STRUCTURES AND METHODS
FOR INSPECTING THE SAME

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Signed: _____

Natalie Morgan

AMENDMENT A

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

It is respectfully submitted that the Examiner enters the following amendments in response to the Office Action dated 6 November 2002, a response to which is due on 6 February 2003.

In the Claims:

Please substitute the following clean claims 7, 54, and 58 for any previous corresponding claims. Additionally, please add the following new claim 107. A marked up version of the claims is presented in the attached Appendix.

7. (Amended Once) A method of fabricating a semiconductor die, comprising:
providing a semiconductor die having a plurality of first areas which are specified by a design as containing structures selected from a group consisting of a product structure and a test structure;